



אוניברסיטת בן-גוריון בנגב
Ben-Gurion University
of the Negev

Nano-Fabrication
Center

Woollam alpha-SE[®] Ellipsometer I



Description

Using for routine measurements of thin film thickness and refractive index for one- and multi-layer structures.

This ellipsometer allows to mount a sample, choose the model that matches your film and press "measure" to get results.

Phase information of a spectroscopic ellipsometry measurement is highly sensitive to very thin films (<10nm).

Single-layer dielectrics on silicon or glass substrates can be measured in seconds.

Also can be measured: Oxides on Si; Transparent thin films; Glass substrate; Metal substrates; Organic monolayers on Gold; Absorbing thin films; Multilayers; etc.

Specifications / Capabilities

Spectral range - 380nm to 900nm, 180 wavelengths

Angle of incidence - 65, 70, or 90 degree (straight - through)

Data Acquisition rate - 3 sec., 10sec. and 30 sec. for high precision mode.

Spot size - 3mm

Link

http://www.jawoollam.com/alphase_home.html